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INFORMATION DISCLOSURE STATEMENT BY APPLICANT

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Sheet 1 of 2

Complete if Known	
Application Number	09/826,583
Filing Date	04/06/01
First Named Inventor	Marc A. Unger
Group Art Unit	1772
Examiner Name	Unassigned
Attorney Docket Number	20174-003010US

U.S. PATENT DOCUMENTS

Examiner Initials *	Cite No.[1]	U.S. Patent Document Number	Kind Code[2] (if known)	Name of Patentee or Applicant of Cited Document	Date of Publication of Cited Document MM-DD-YYYY	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
[illegible]	1	6,174,365	B1	Sanjoh	01-16-2001	
	2	6,007,309		Hartley	12-28-1999	
	3	5,876,187		Afromowitz et al.	03-02-1999	
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		Office[3]	Number[4]	Kind Code[5] (if known)				
	20	WO	99/17093	A1		04-08-1999		
	21	WO	98/07069	A1		02-19-1998		
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Sheet 1 of 3

Complete If Known	
Application Number	09/826,583
Filing Date	04/06/01
First Named Inventor	Marc A. Unger
Group Art Unit	1772
Examiner Name	Unassigned
Attorney Docket Number	20174-003010US

OTHER PRIOR ART -- NON PATENT LITERATURE DOCUMENTS			
Examiner Initials *	Cite No.[1]	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T[2]
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Sheet 1 of 2

Complete if Known	
Application Number	09/826,583
Filing Date	April 6, 2001
First Named Inventor	Unger et al.
Art Unit	3753
Examiner Name	Chambers, A.M.
Attorney Docket Number	20174C-003010US

U.S. PATENT DOCUMENTS

Examiner	Cite No.[1]	Document Number: Number Kind Code[2] (*if known*)	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
	AA	6,043,080	03-28-2000	Fodor et al.	
	AB	5,681,024	10-28-1997	Lisec et al.	
	AC	5,346,372	09-13-1994	Naruse et al.	
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	AE	5,088,515	02-18-1992	Kamen, D.	
	AF	4,245,673	01-20-1981	Bouteille et al.	

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Examiner Initials*	Cite No.[1]	Foreign Patent Document: Country Code[3] Number[4] Kind Code[5] (*if known*)	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear	T[6]
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Examiner Signature		Date Considered	01/04

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Sheet 2 of 2

Complete if Known	
Application Number	09/826,583
Filing Date	April 6, 2001
First Named Inventor	Unger et al.
Art Unit	3753
Examiner Name	Chambers, A.M.
Attorney Docket Number	20174C-003010US

OTHER PRIOR ART -- NON PATENT LITERATURE DOCUMENTS			
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AMU	AG	Quake et al., "From Micro- to Nanofabrication with Soft Materials," Science, 290:1536-1540 (2000).	
AMU	AH	Unger et al., "Monolithic Microfabricated Valves and Pumps by Multilayer Soft Lithography," Science, 288:113-116 (2000).	
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Sheet 1 of 1

Complete If Known	
Application Number	09/826,583
Filing Date	April 6, 2001
First Named Inventor	Marc A. Unger
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Examiner Name	Michael A. Chambers
Attorney Docket Number	20174C-003010US

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	1	US 6,174,675 A	01-16-2001	Chow et al.	
	2	US 5,958,694 A	09-28-1999	Theo T. Nikiforov	
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